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# Effect of Phosphorus on Ge/Si(001) Island Formation

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**[www.hpl.hp.com/research/qsr](http://www.hpl.hp.com/research/qsr)**

**Presented at Fall Meeting of the  
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December 2, 2002**



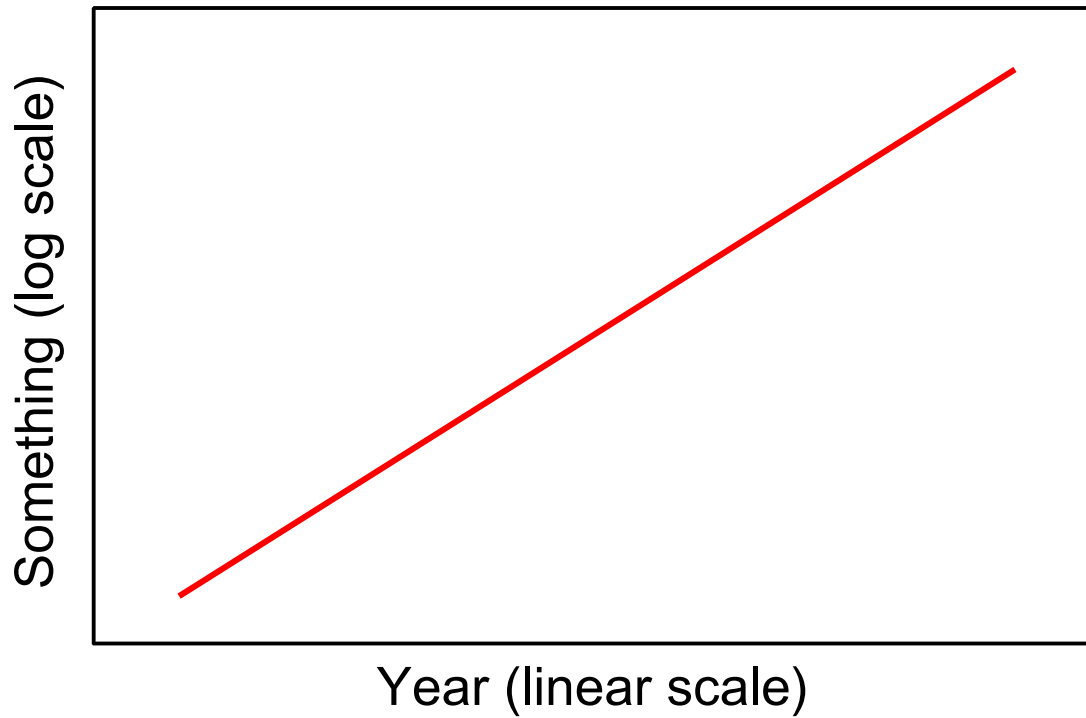
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# Outline

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- Limits of Moore's law
- Forming a feature using "self assembly"
- Strain from lattice mismatch between two materials
- Ge islands on Si substrate
  - Undoped
  - **Phosphorus doped**
- Thermodynamics vs. kinetics

## Moore's Law (General Case)

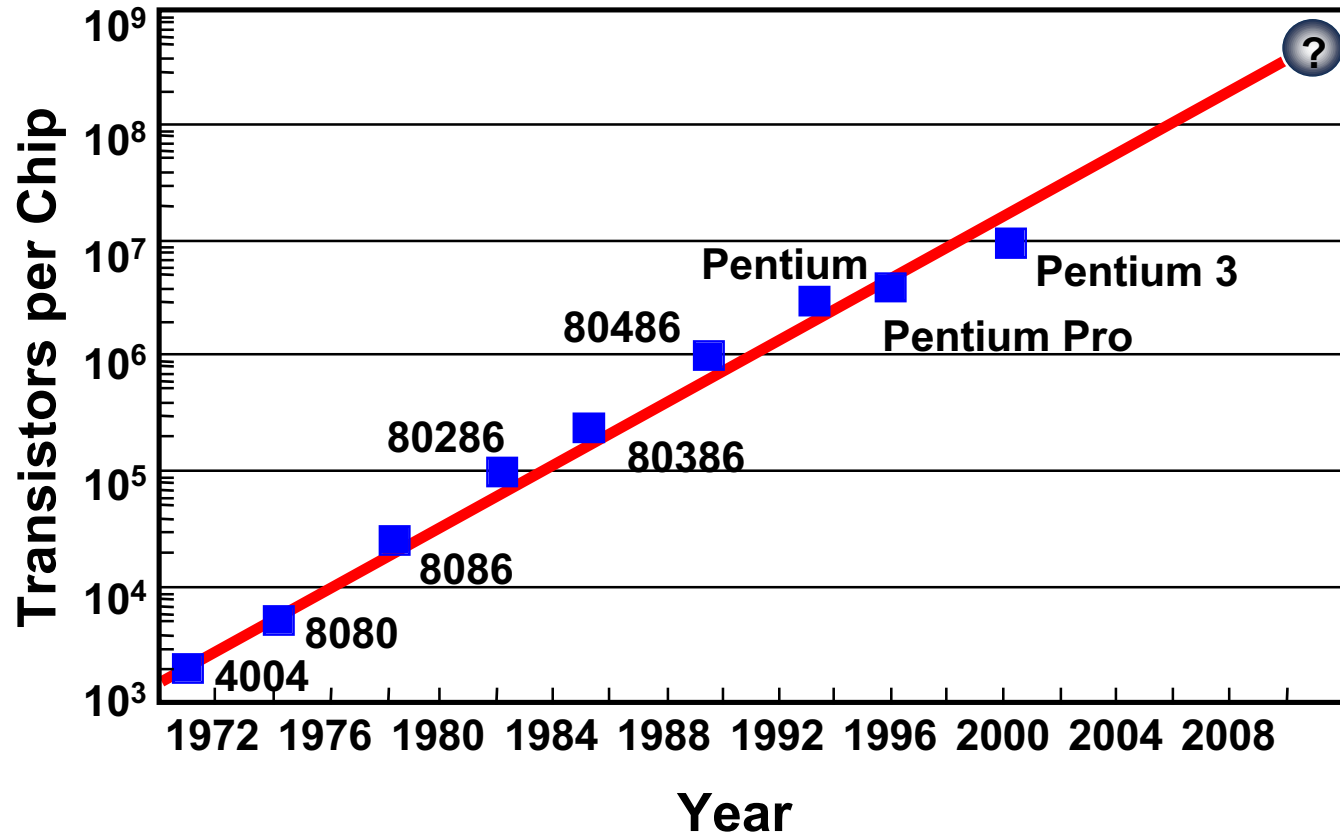


### **Even Dilbert uses Moore's Law**

(Reference: Scott Adams "Dilbert," July 15, 1997)

# Moore's Law

## Number of Transistors



# Critical Issues

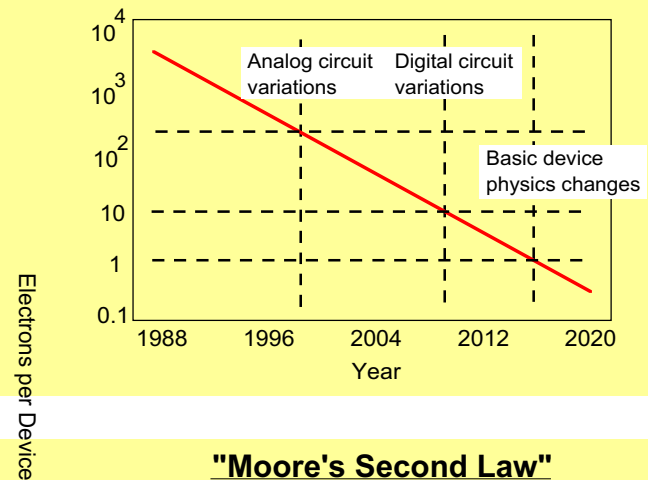
## Device size and density

- Physically small features
- Operation with small features
- Limited number of electrons
- Interconnections

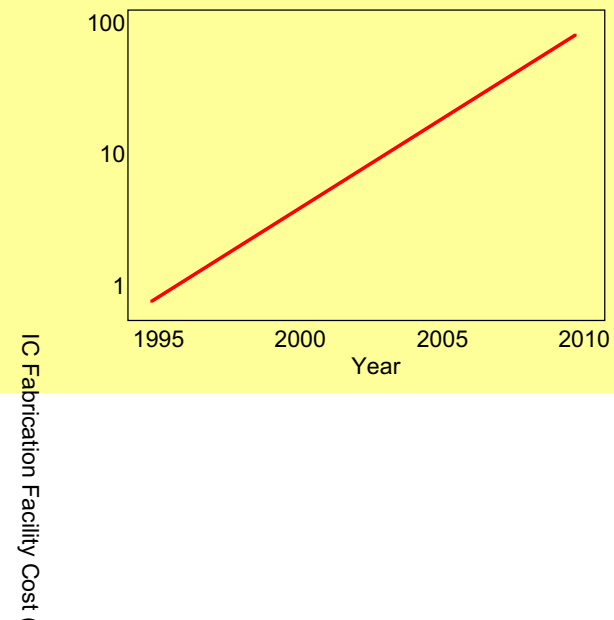
## Cost ("Moore's second law")

- Simpler architecture
- Defect-tolerant architecture
- Minimize expensive lithography
- Self (or directed) assembly

**Moore's Law**  
(Number of Electrons)



**"Moore's Second Law"**  
Cost of IC Fabrication Facility



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# Self-Assembled Nanostructures

## 0D Islands and 1D Nanowires on Si

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### **Conventional scaling will reach its limits**

Use self and directed-assembly to extend Moore's law  
Determine critical dimensions by choice of materials and deposition kinetics ("self assembly"), not lithography  
Use lithography to position devices or arrays of devices ("directed assembly")

### **Use small-size effects for logic, storage, and computation**

Coulomb blockade  
Quantum confinement

### **Methods of self- or directed- assembly**

Strain from lattice mismatch  
Catalytic wire growth on nanoparticle

### **Thermodynamically assembled structures**

Several percent defects  
Need defect-tolerant architecture



# Forming Self-Assembled Islands (Quantum Dots)

## Deposit one material on another

Different lattice constants → strain

Large strain → islands

$$(\epsilon_x = \epsilon_y)$$

Small islands → quantum or

Coulomb-blockade effects

Island shape determined by  
volume, facet, interface,  
and edge energies

## Focus on Ge on Si

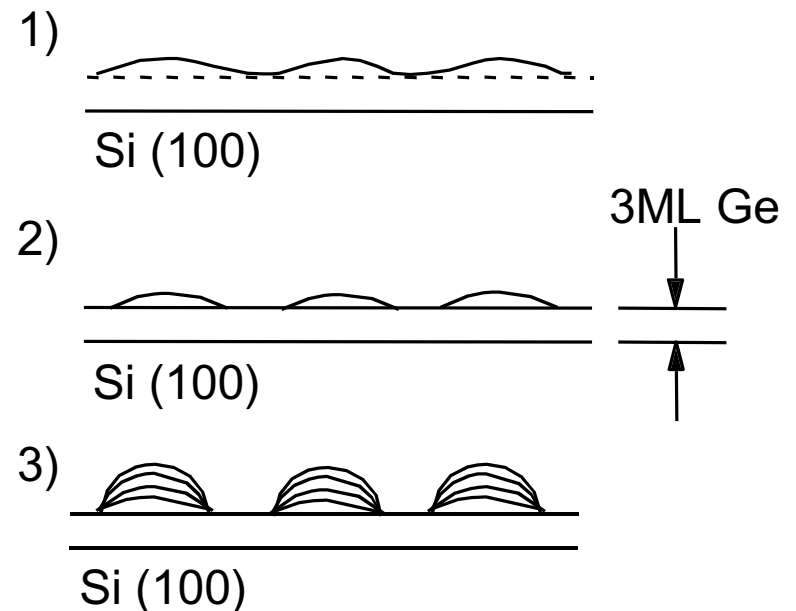
Why Ge on Si?

Compatible with Si IC technology

Model system



## Energy and Kinetics Influence Island Formation



# Undoped Ge Islands

## Deposition by

CVD:  $\text{GeH}_4 + \text{H}_2$

PVD: e-beam evaporation

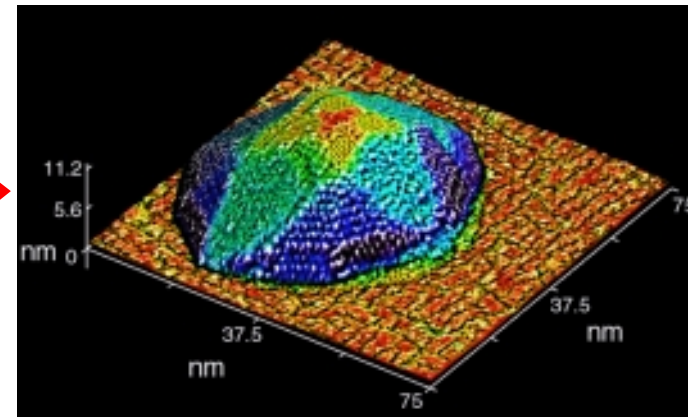
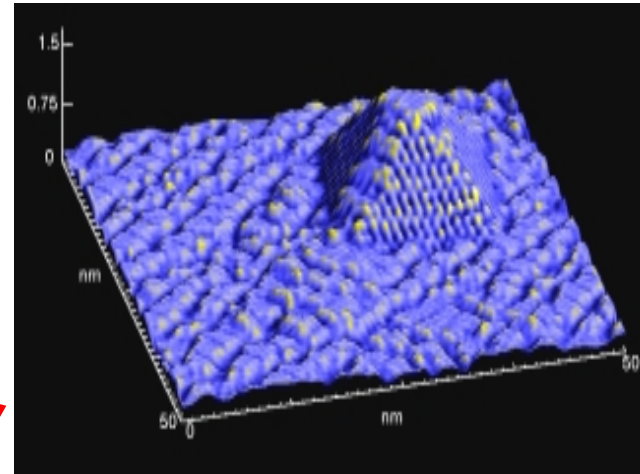
**<4 ML Ge:** Uniform Ge layer  
No islands

## Three types of islands:

**6 eq-ML:** Pyramids  
Bounded by  $\{105\}$  facets

**11 eq-ML:** Domes  
Taller to reduce interface area  
Bounded by steeper facets  
Strain relaxation near top of island

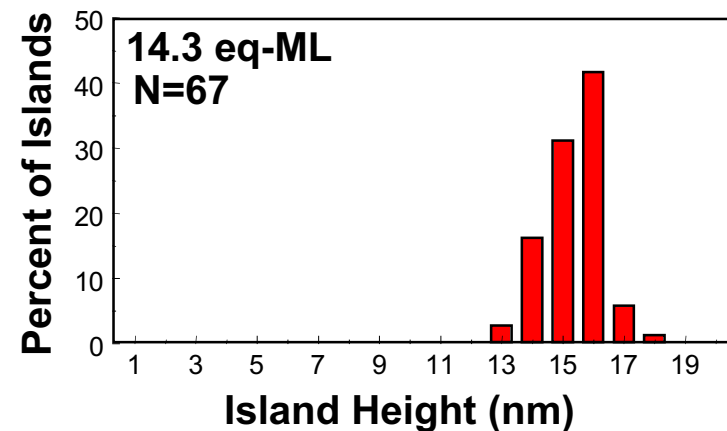
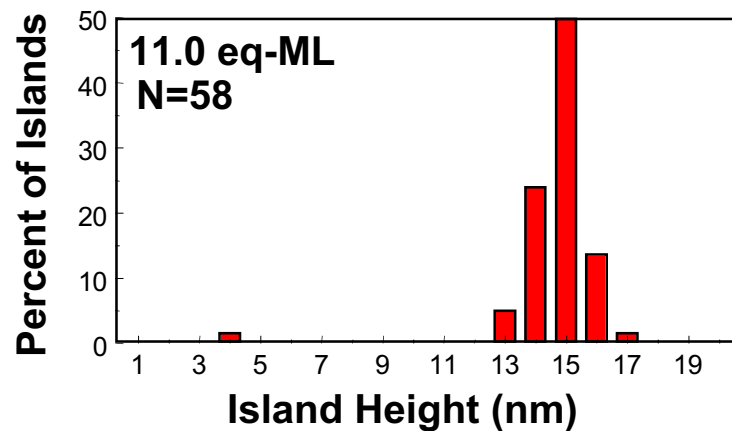
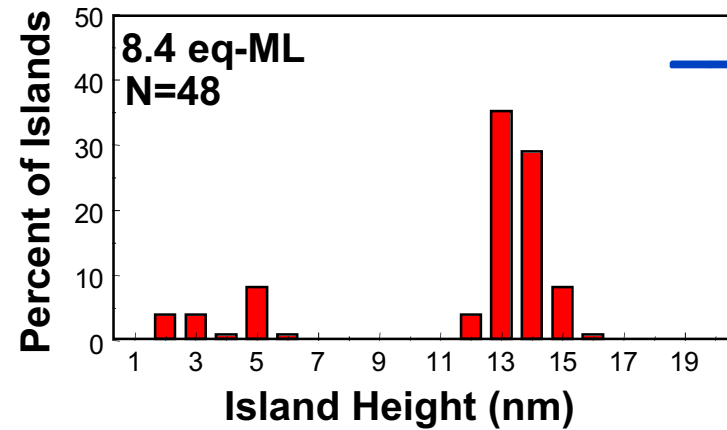
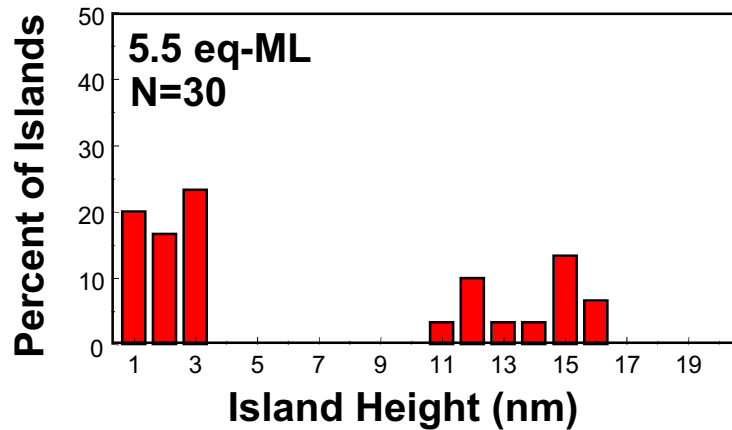
**>14 eq-ML:** "Super-domes"  
Steep facets; defects



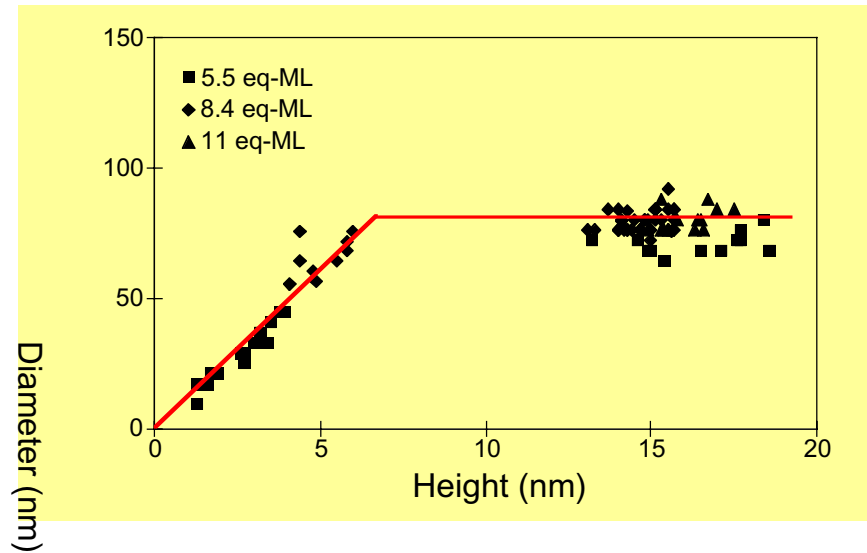
Scanning Tunneling Micrographs  
by G. Medeiros-Ribeiro, HPL&LNLS



# Distribution of Island Heights

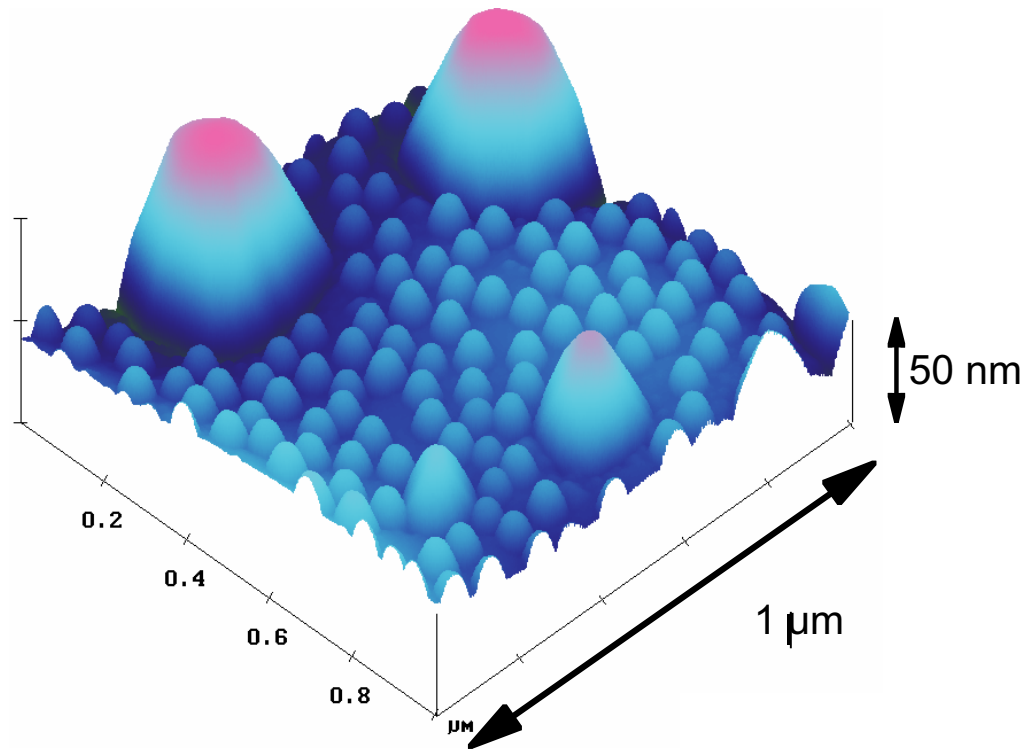


# Island Distribution



Domes have favored size  
Pyramids do not

**Ge/Si(001): ~44 eq-ML at 600°C**  
**(Barrier to Dome Growth)**



# Manipulating Islands

Domes have narrower distribution  
Potentially more useful

How to get smaller domes?

Add something that binds well  
to surface, changes surface  
energy (and perhaps ratio of  
energies of different surfaces)

- Add HCl during deposition:  
Primarily changes kinetics
- Etch with HCl after deposition  
Reduces island height, not base
- Use Ti ( $\text{TiSi}_x$ )  
Larger lattice mismatch  
(But Ge/Si system beneficial)
- Add other impurities to Ge/Si



# Manipulating Islands

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Potentially more useful

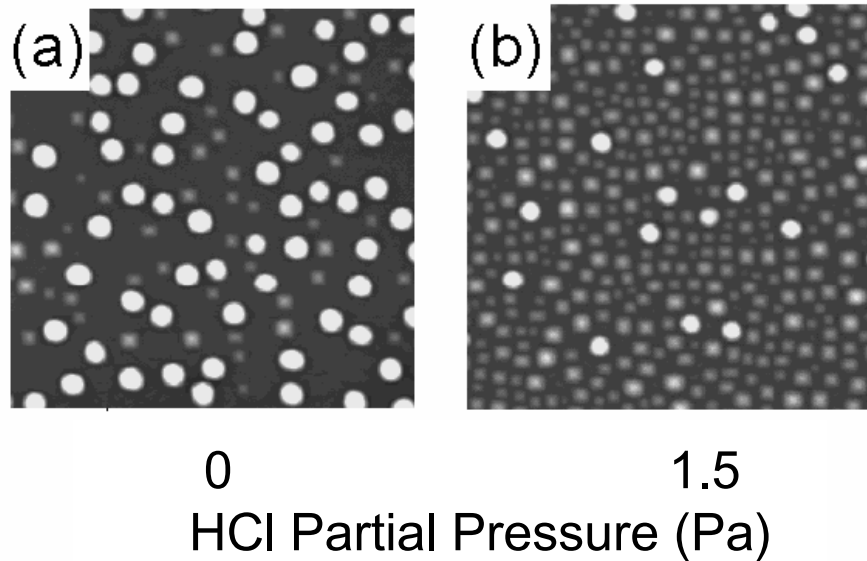
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## Using HCl to Control Islands

Adding HCl during Deposition



Adsorbed Cl impedes Ge surface diffusion

Changes kinetics, rather than thermodynamics

# Manipulating Islands

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Potentially more useful

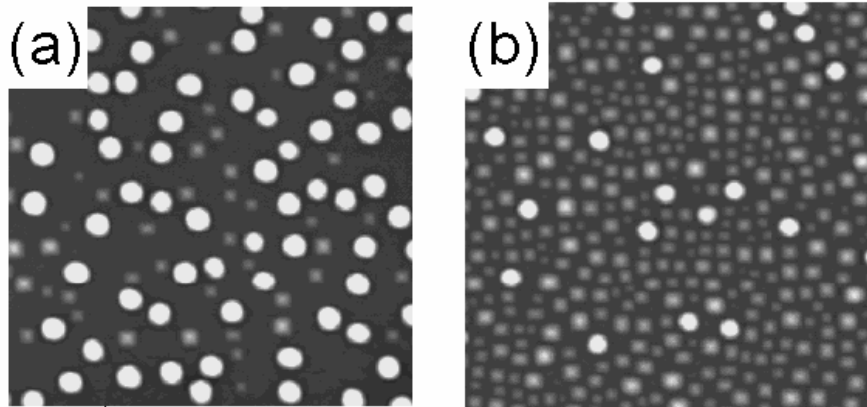
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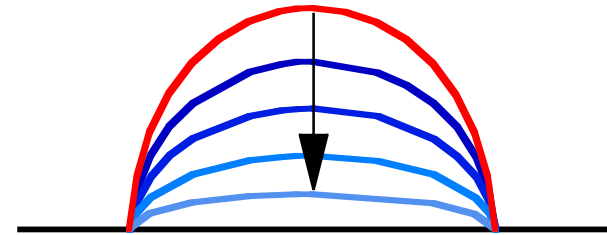
# Using HCl to Control Islands

Adding HCl during Deposition



0  
1.5  
HCl Partial Pressure (Pa)

Etching with Gaseous HCl  
after Deposition



Shorter, but not narrower

Adsorbed Cl impedes Ge surface diffusion

Changes kinetics, rather than thermodynamics



# Manipulating Islands

Domes have narrower distribution  
Potentially more useful

How to get smaller domes?

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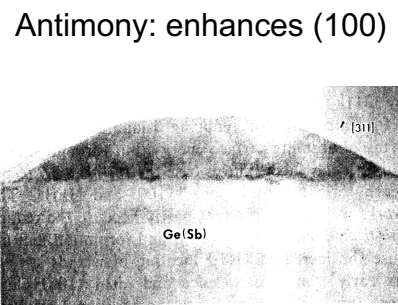
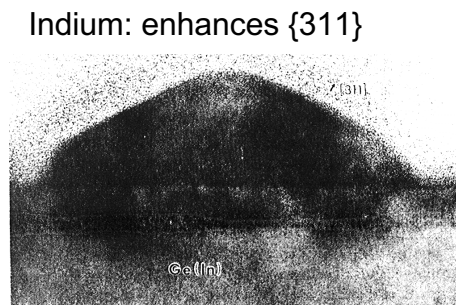
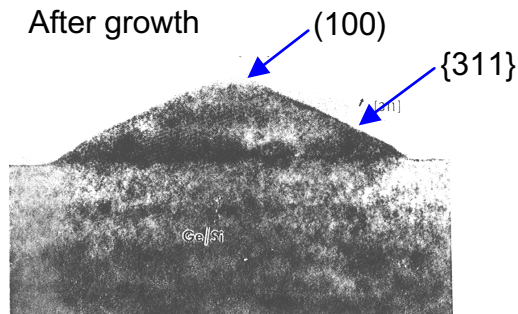
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Larger lattice mismatch  
(But Ge/Si system beneficial)
- **Add other impurities to Ge/Si**



# Effect of Impurities on Equilibrium Island Shape



D. J. Eaglesham, F. C. Unterwald, and D. C. Jacobson,  
Phys. Rev. Lett. 70, 966 (1993)

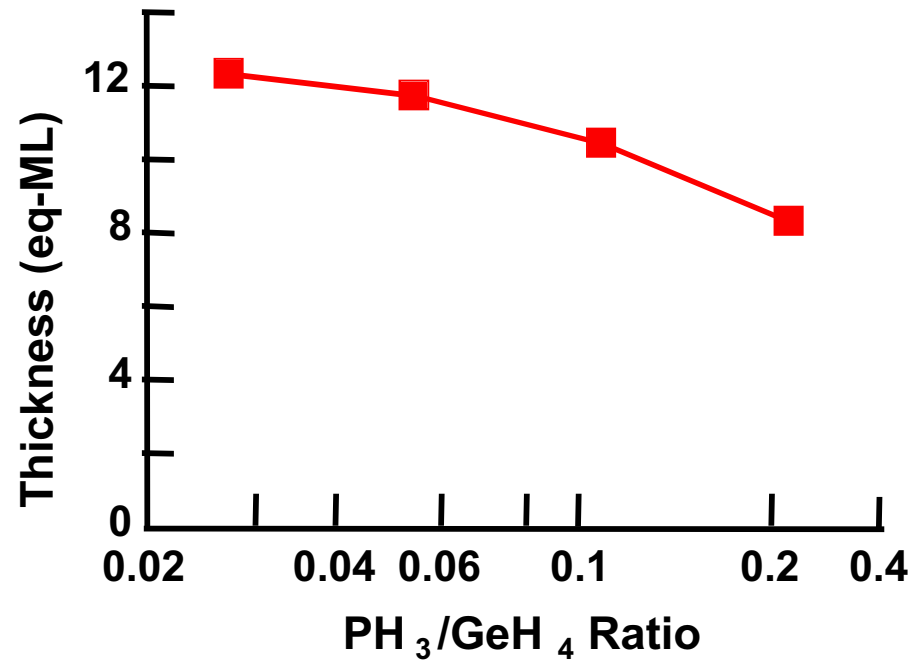
Surface impurities change  
surface energy *anisotropy*

Phosphorus or arsenic  
*n*-type dopants  
Initiation of arsenic  
incorporation slow  
Little in thin layer

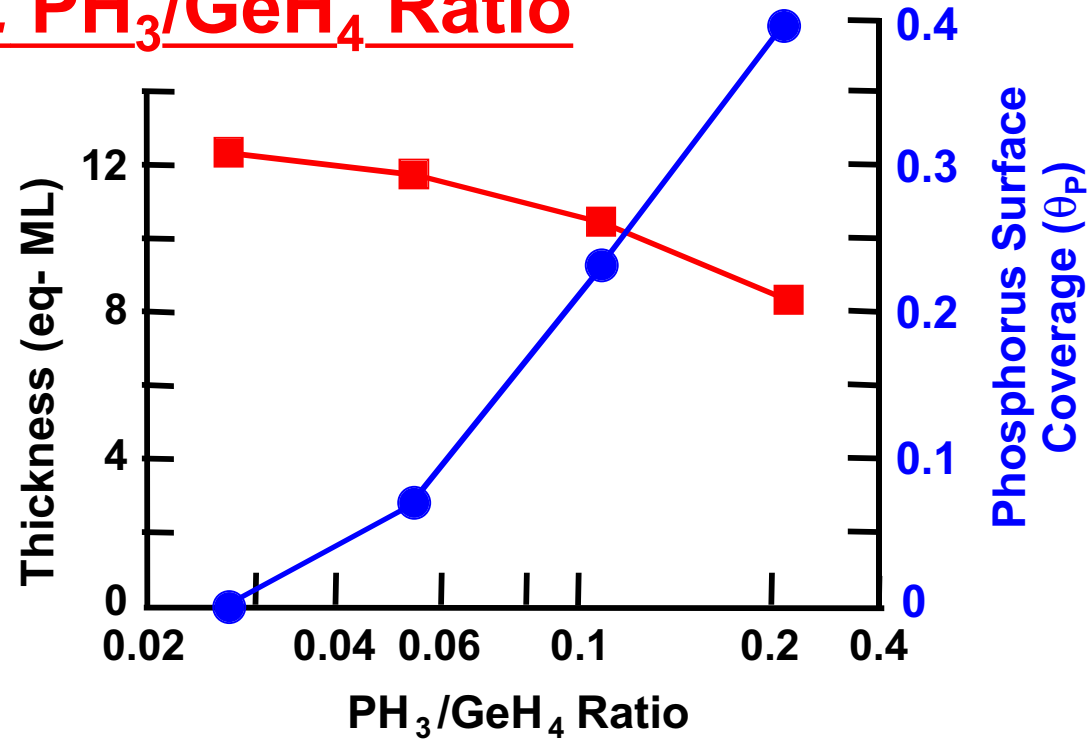
**Phosphorus** more useful as  
dopant

Thermodynamics vs. kinetics

# Ge Thickness vs. $\text{PH}_3/\text{GeH}_4$ Ratio Competitive Adsorption



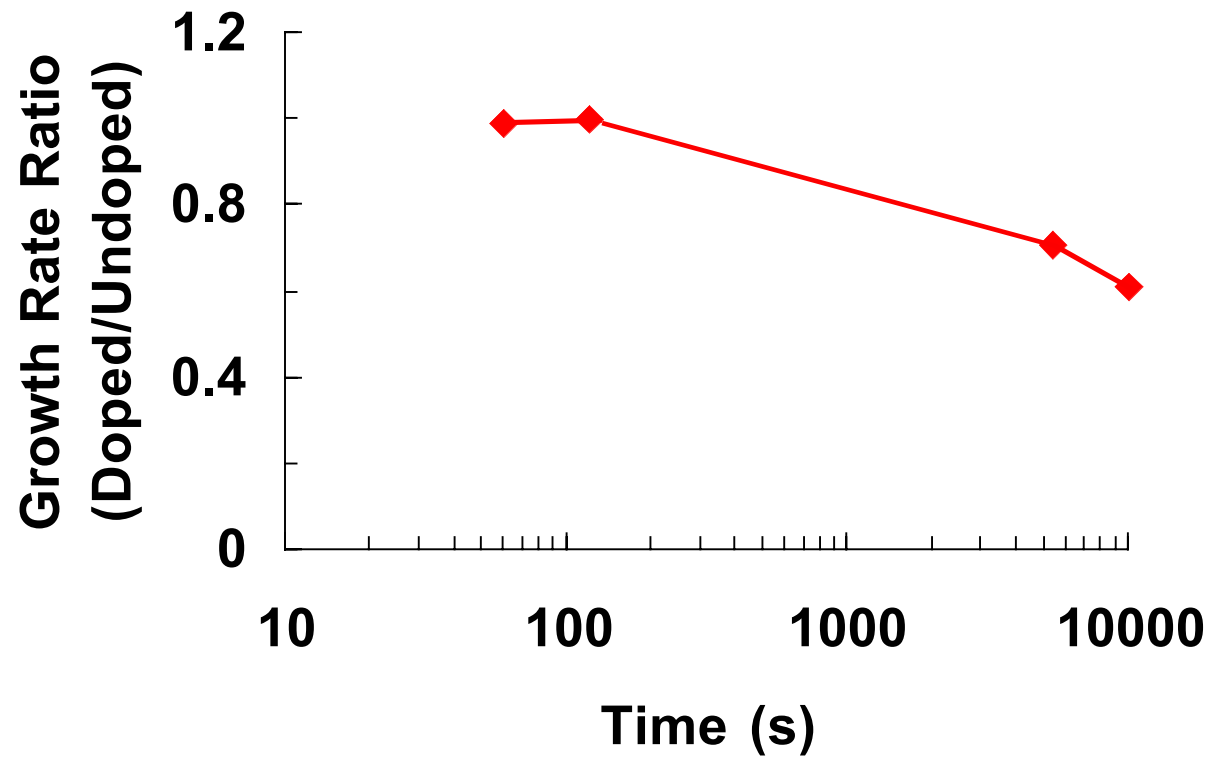
# Phosphorus Surface Coverage vs. $\text{PH}_3/\text{GeH}_4$ Ratio



$$\theta_P = \frac{C_P \exp(-\Delta H/kT)}{n_{\text{Ge}} - C_P [1 - \exp(-\Delta H/kT)]}$$

$$\Delta H \sim -0.4 \text{ eV}$$

## Growth Rate Ratio vs. Time



Slow increase of surface phosphorus concentration

# Doped Ge islands



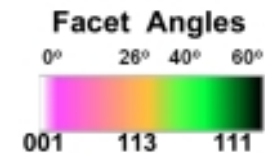
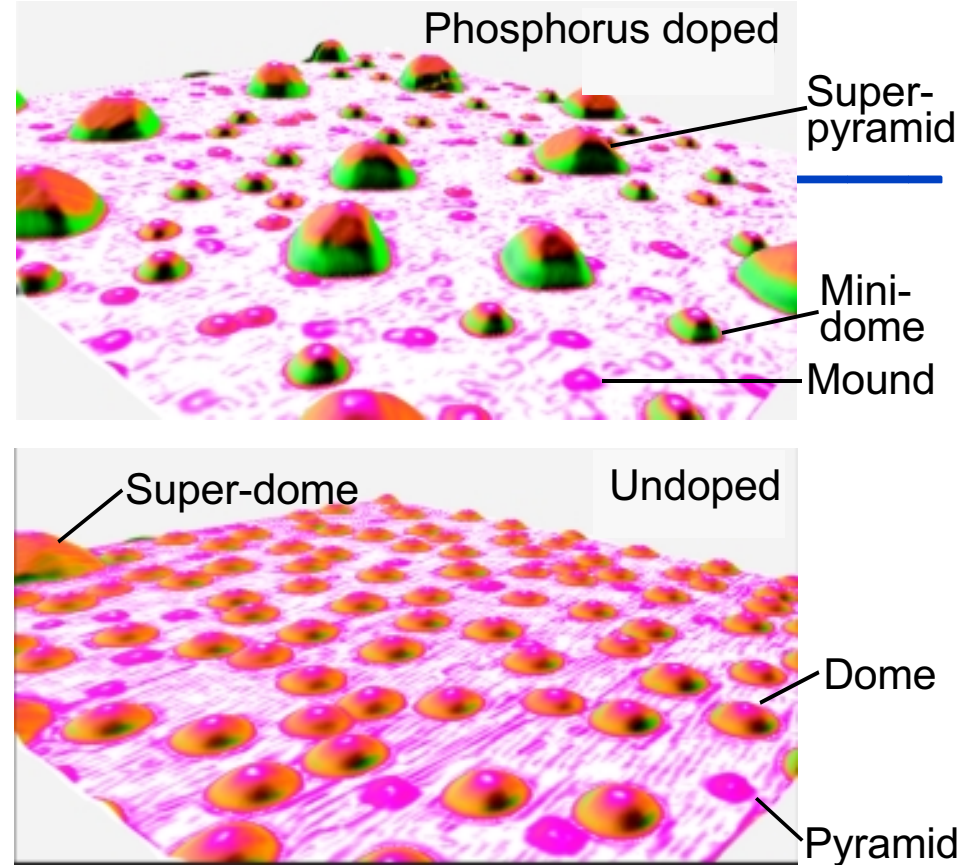
Temperature: 600°C

Partial pressures:

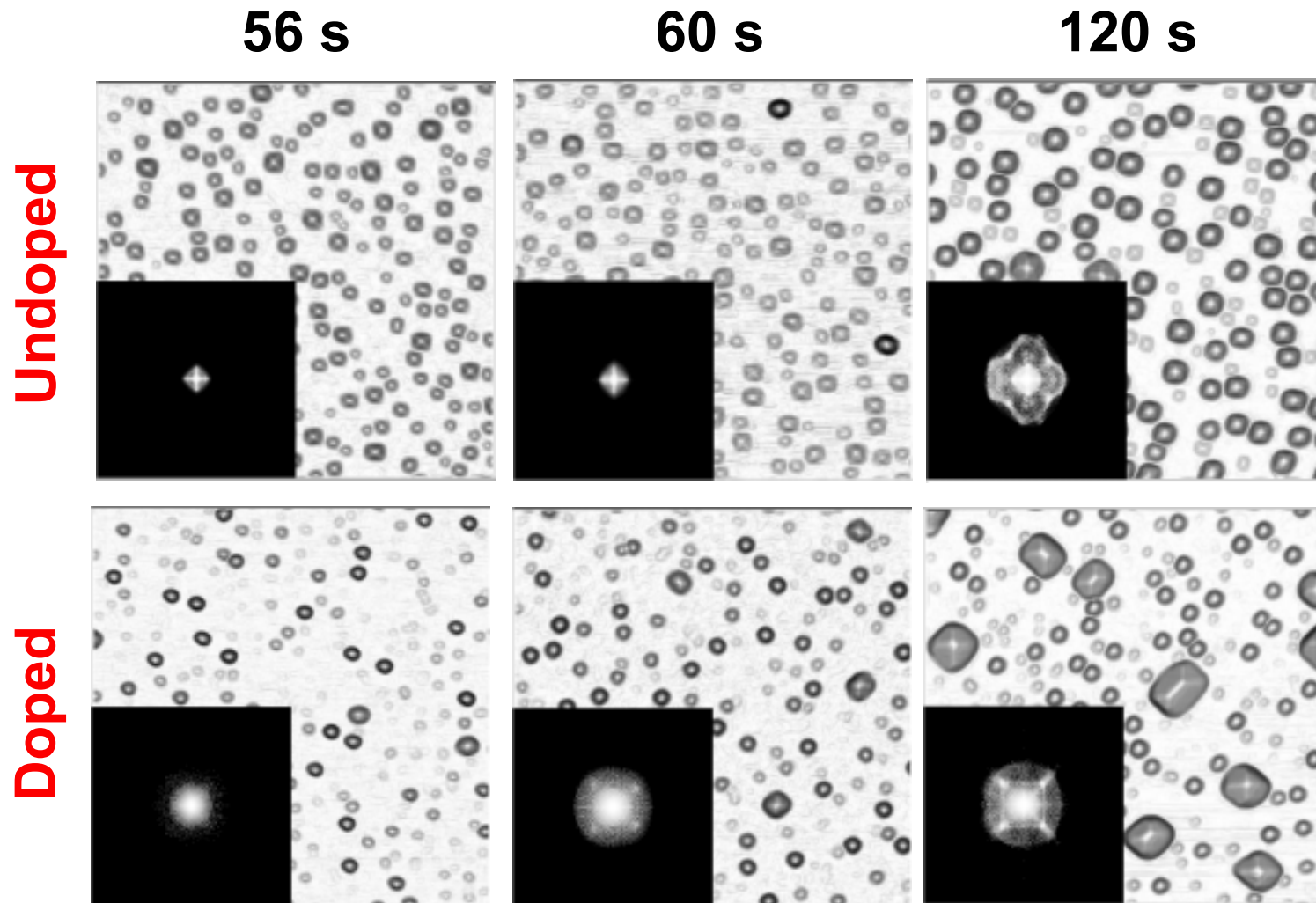
$\text{H}_2$ : 1.3 kPa (10 Torr)

$\text{GeH}_4$ :  $3\text{-}6 \times 10^{-2}$  Pa ( $2.5\text{-}5 \times 10^{-4}$  Torr)

$\text{PH}_3$ :  $1.7 \times 10^{-3}$  Pa ( $1.4 \times 10^{-5}$  Torr)

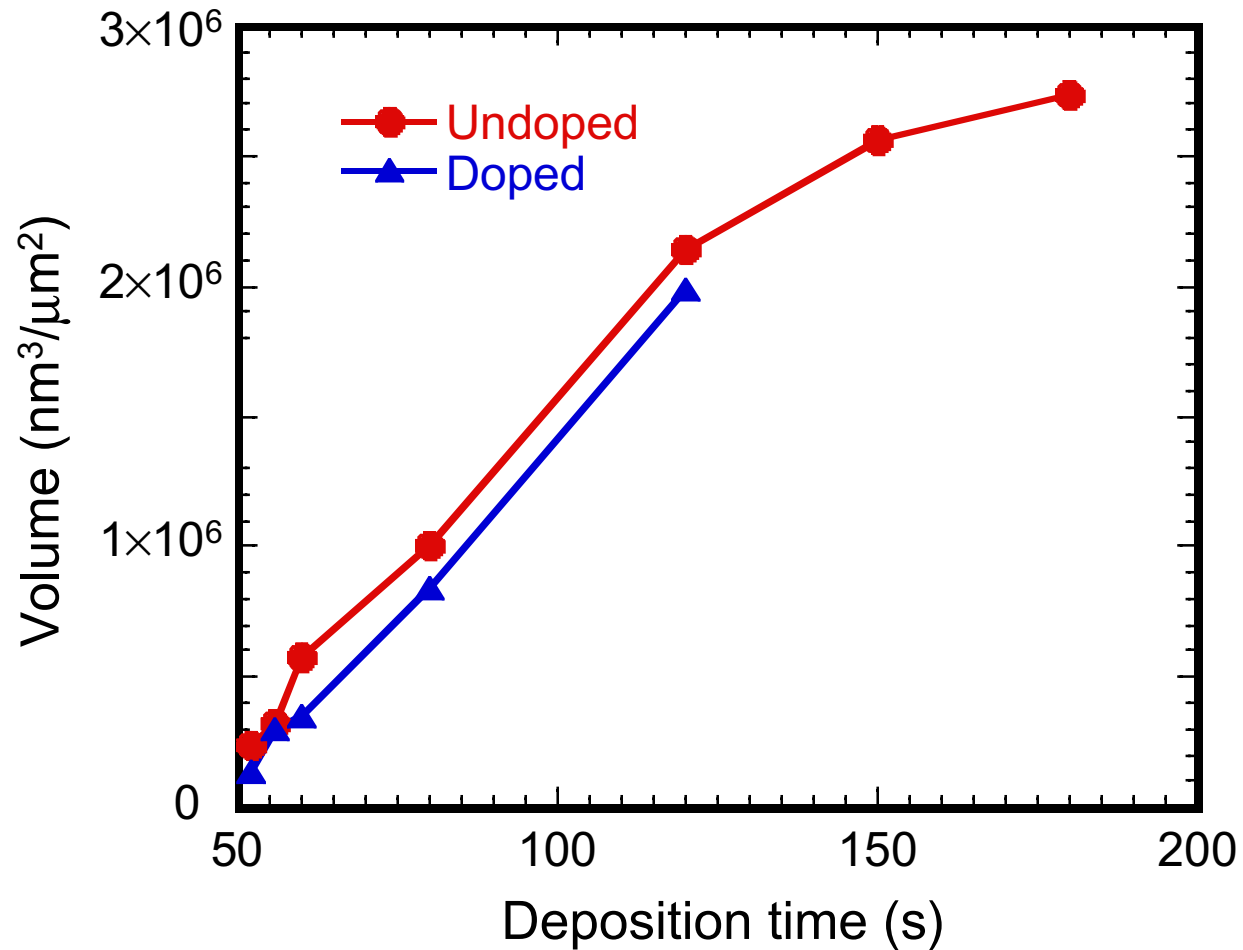


# Shape evolution: Doped vs. undoped



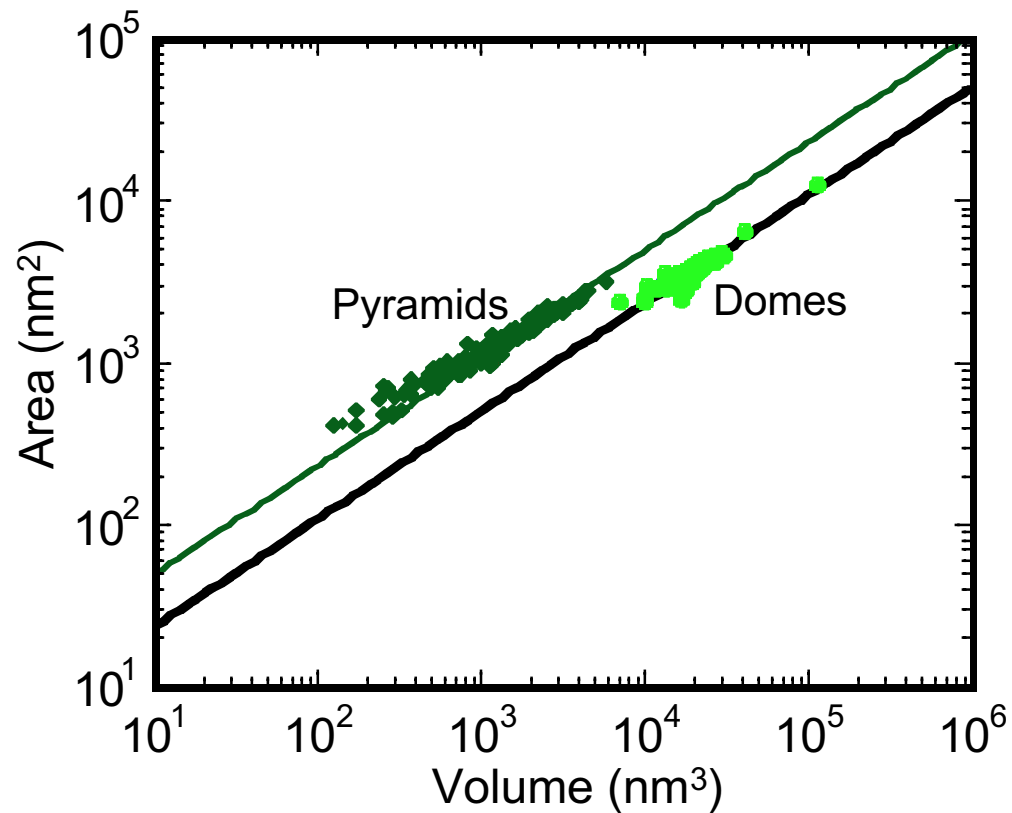


# Island Volume: Doped vs. undoped Integrated AFM volumes vs. deposition time



# Island Shape Analysis

Points of one shape lie on line with slope = 2/3  
Different intercept for different shapes  
Undoped: Pyramids and Domes



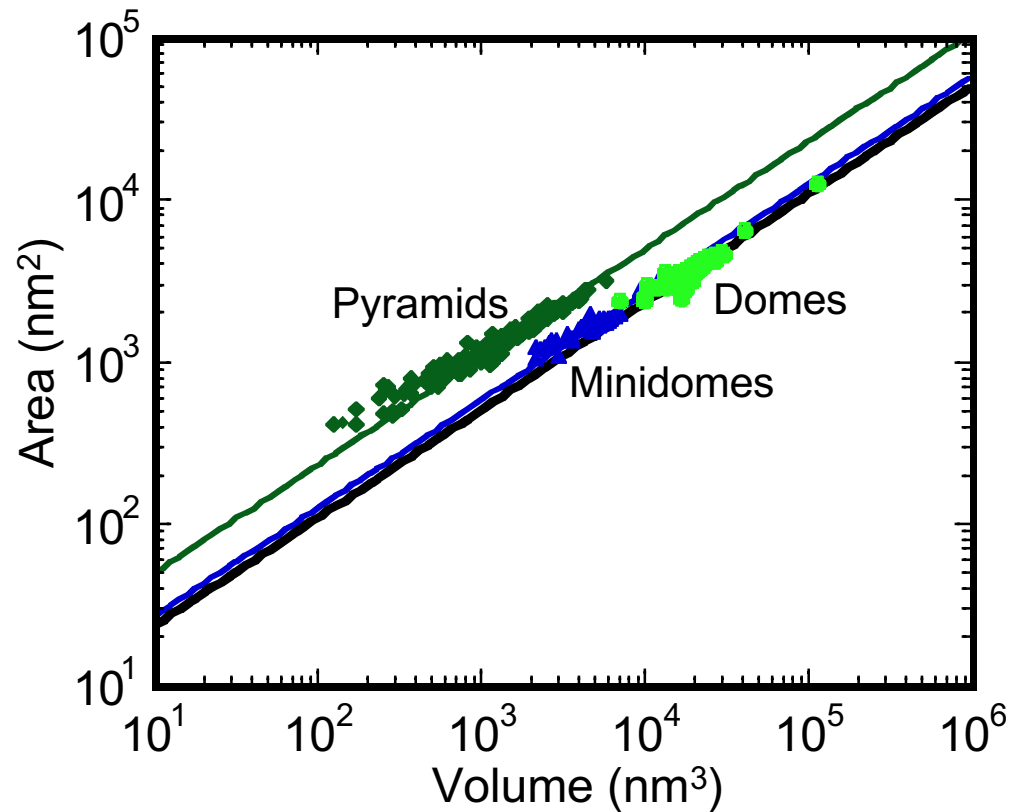
# Island Shape Analysis

Points of one shape lie on line with slope =  $2/3$

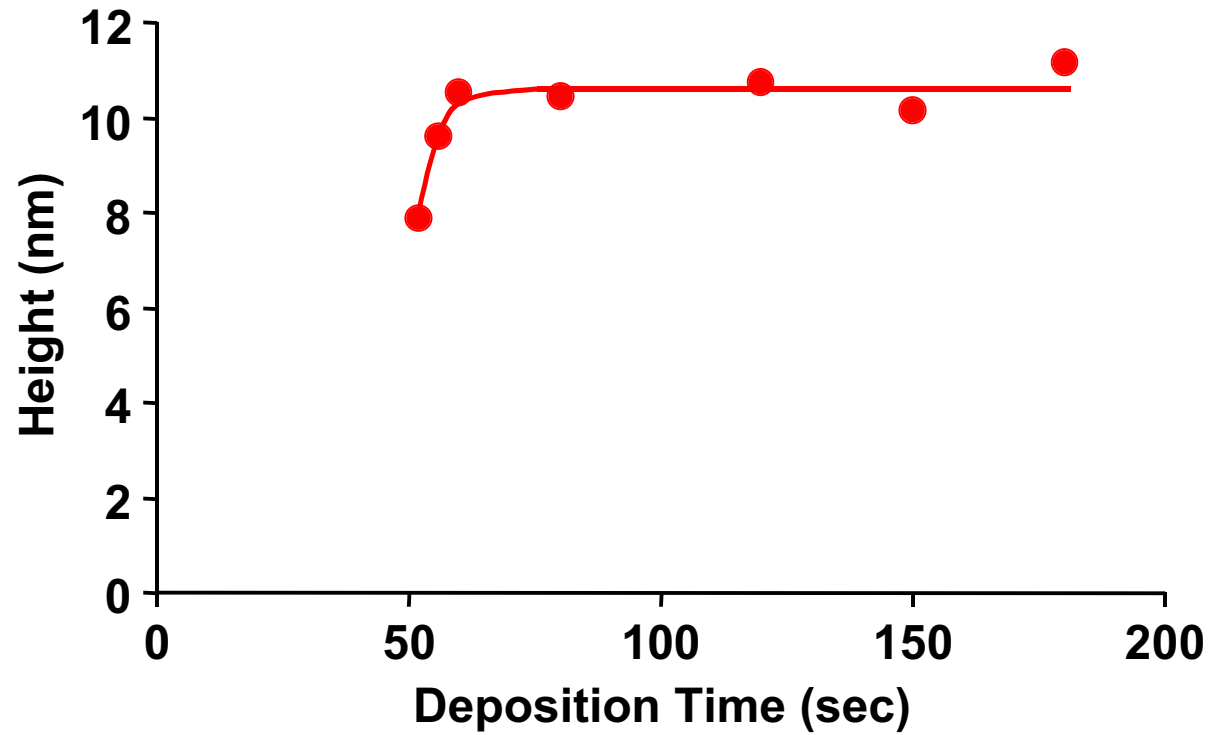
Different intercept for different shapes

Undoped: Pyramids and Domes

Doped: Mini-domes

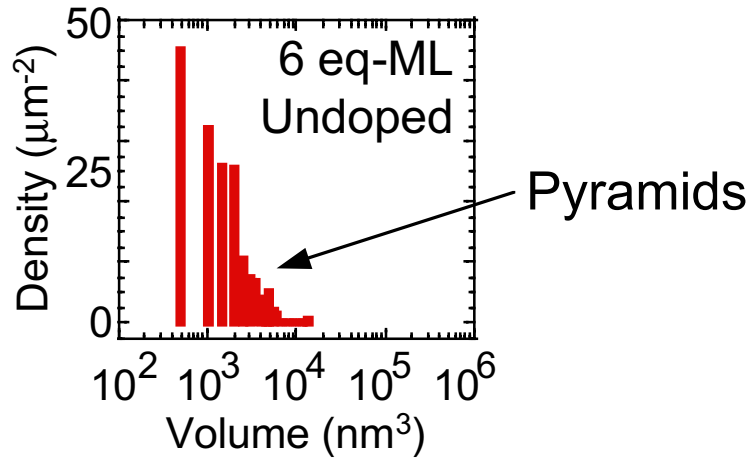


## Mini-Dome Height



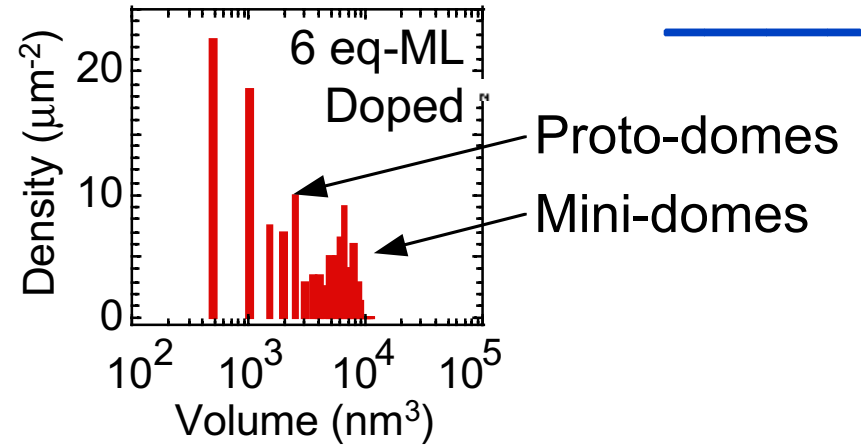
# Undoped Ge islands

6 eq-ML

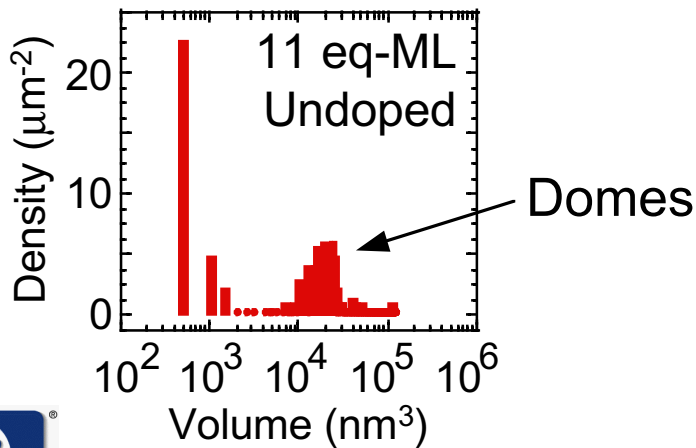


# Doped Ge islands

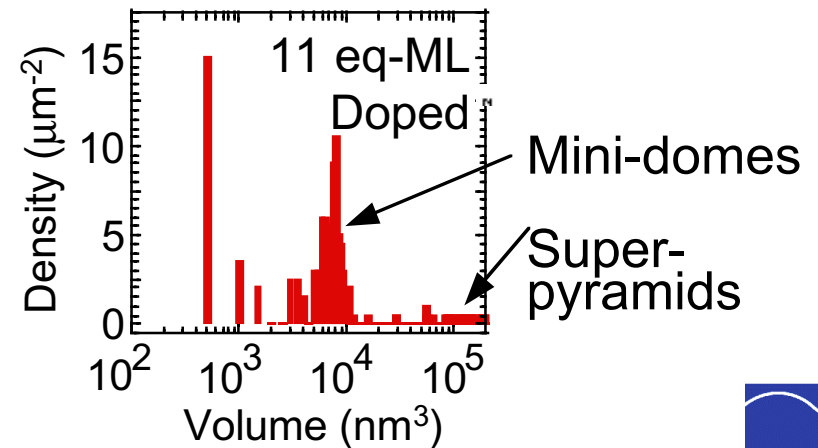
6 eq-ML



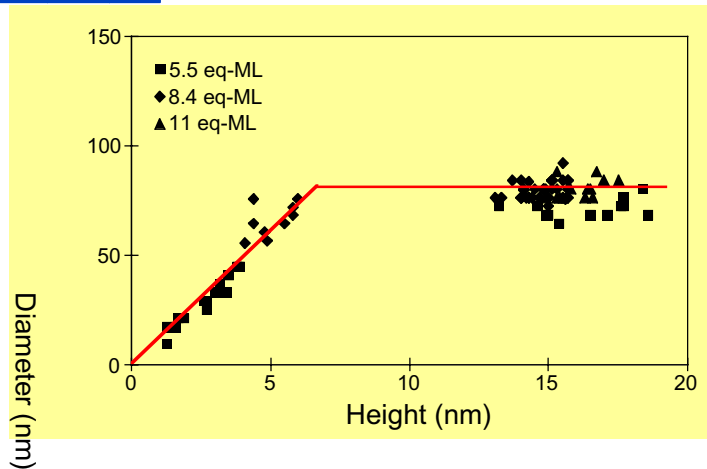
11 eq-ML



11 eq-ML

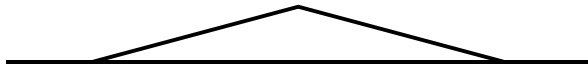


## Island Distribution



Domes have favored size  
Pyramids do not

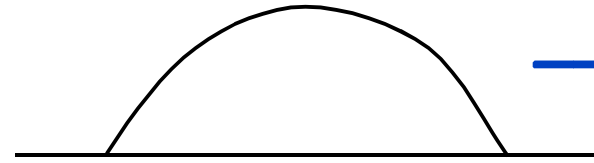
## Pyramids



Bounded by {105} facets only  
Proportional:  
Surface area  
Interface area  
Edge length



## Domes

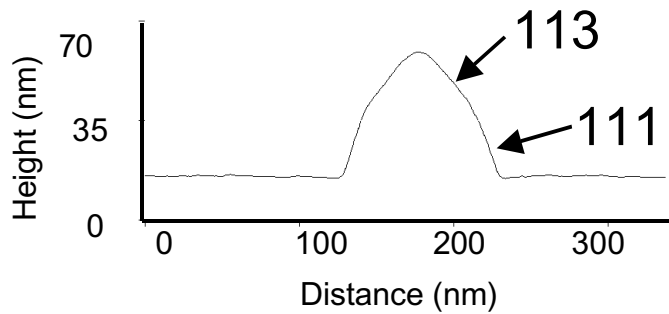
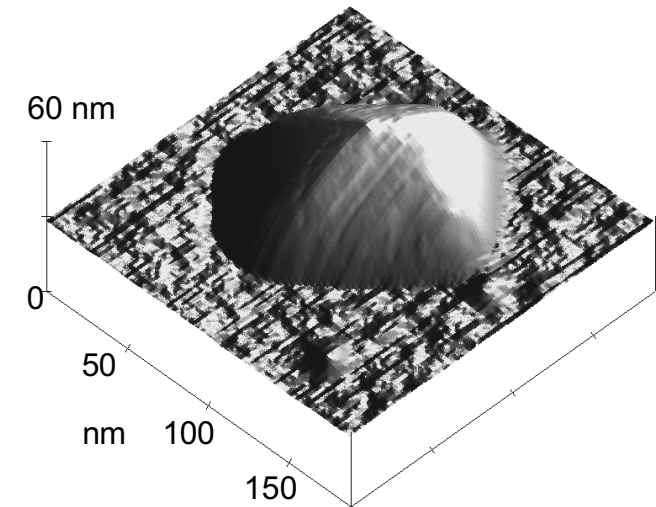


Bounded by several facets  
Area ratio can vary  
Need not be proportional:  
Surface area  
Interface area  
Edge length  
Can vary to minimize energy  
Harder to add atoms beyond  
this energy minimum

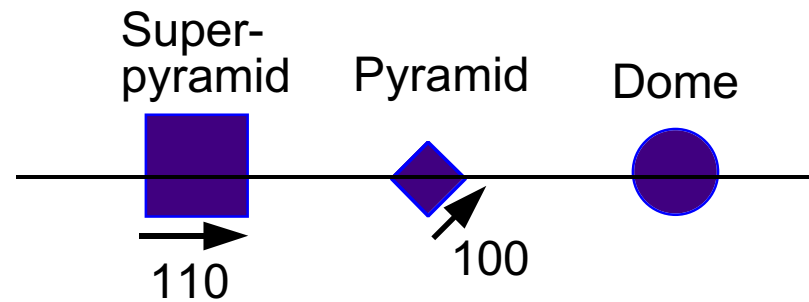
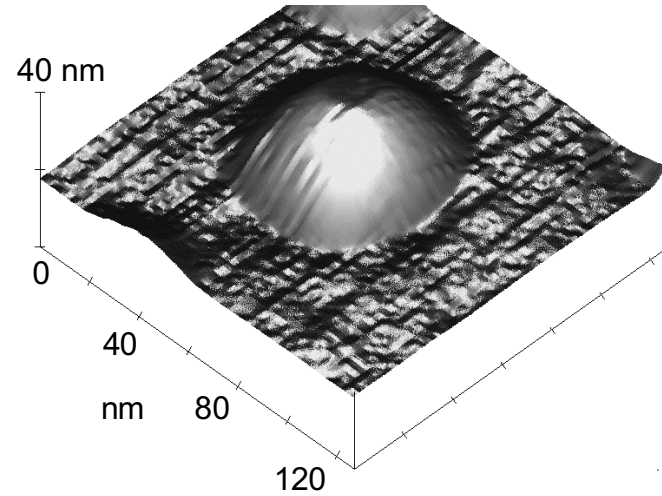
Strain relaxation near top of island



# “Superpyramid”

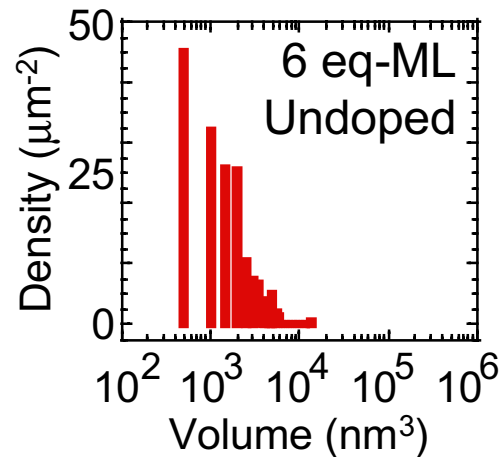


# For comparison: Dome



# Phosphorus Also Changes Annealing Kinetics

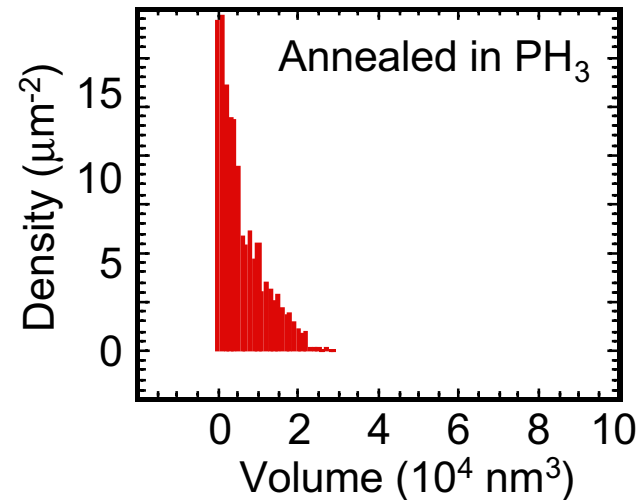
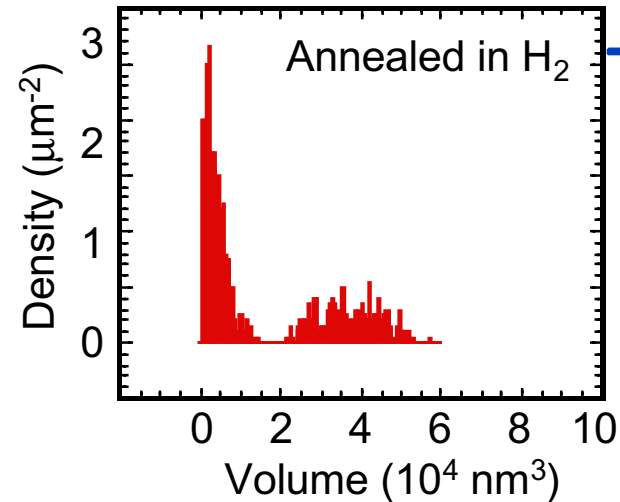
6 eq-ML undoped Ge  
Mainly pyramids



## Effect of annealing

$\text{H}_2$ : Islands coarsen  
Many pyramids  
convert to domes

$\text{PH}_3$ : Coarsening retarded





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# Summary

## Phosphorus-Doped Ge/Si Islands

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- Phosphorus...
  - Modifies energies and relative energies of different surface planes
  - Changes favored island shapes
  - Island shape influenced by surface energy (Thermodynamics)
  - Retards coarsening (Kinetics)
- Additional method for controlling island size, shape, and uniformity
- Deposition rate decreases with increasing  $\text{PH}_3/\text{GeH}_4$  ratio and increasing time
  - Slow increase of surface phosphorus
  - $\text{PH}_3$  changes island shape in thin layers → Significant phosphorus on surface in thin layers
- Phosphorus concentration near solid solubility limit ( $\sim 5 \times 10^{19} \text{ cm}^{-3}$ ) (SIMS)